

Analysis of Permanent Gases and Light Hydrocarbons Using Agilent 7820A GC With 3-Valve System

Application Note

HPI

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Highlights

- Agilent 7820A GC 3-valve system provides a low-cost but powerful platform for analysis of permanent gases and light hydrocarbons.
- Full electronic pneumatics control (EPC) provides an easy-to-use operation for the end user and ensures excellent repeatability for both retention time and peak area.
- This application work can also be used as a reference in the analysis of natural gas, petroleum gas, synthesis gas, purified gas, water gas, blast furnace gas, stack gas, and so on.

Abstract

A new economical solution is provided to test permanent gases and light hydrocarbons. An Agilent 7820A Gas Chromatograph equipped with three valves, a flame ionization detector (FID), and a thermal conductivity detector (TCD), is configured for analysis of permanent gases and light hydrocarbons. The TCD channel with packed columns is used to measure H₂, CO₂, O₂, N₂, CH₄ and CO. A capillary column (Al₂O₃ PLOT: 50 m × 0.53 mm) is used to measure all hydrocarbons (C1~C6) including CH₄.



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Introduction

Analysis of permanent gases and light hydrocarbons has been widely employed in the petrochemical, chemical and energy industries. These permanent gases, such as O₂, N₂, CH₄, CO, and CO₂ are the common target compounds in natural gas, petroleum gas, synthesis gas, purified gas, water gas, blast furnace gas, stack gas, and so on. Understanding the concentrations of these components is important for petrochemical, chemical and energy industrial processes. The 7820A 3-valve system offers an easy-to-use and powerful platform for the analysis of these kinds of samples.

This work illustrates one typical application of the 7820A 3-valve system for the analysis of permanent gases and light hydrocarbons.

Experimental

Three valves were used in this 7820A system: six-port gas sampling, ten-port gas sampling with back-flush to vent, and another six-port column isolation. The valve diagram and columns configuration are shown in Figure 1. Normally, the valve sample loops are connected in series for simultaneous dual-channel injection. Valve control is handled by EZChrom Elite compact software. Chromatographic conditions and valve time events are listed in Tables 1 and 2.

Table 1. Gas Chromatographic Conditions

Sample loop size	0.25 mL
FID channel flow	5 mL/min
FID temp	300 °C
FID channel carrier	N ₂
Capillary splitter temp	200 °C
Split ratio	25:1
TCD channel flow	30 mL/min
TCD temp	250 °C
TCD channel carrier	He
Valve box temp	120 °C
Oven program	45 °C (6 min) >180 °C (2.25 min) at 20 °C/min

Table 2. Time Events

Events	Time (min)
Valve 1 ON*	0.01
TCD Negative Polarity ON	0.6
TCD Negative Polarity OFF	1.4
Valve 2 ON	1.7
Valve 1 OFF*	2.5
Valve 2 OFF	3.2

*Time events of valve 3 are the same as valve 1.

A fixed gas mix standard, (Jiliang Standard Gas Inc., Shanghai), was used in this application test. The components and concentrations are listed in Table 3.

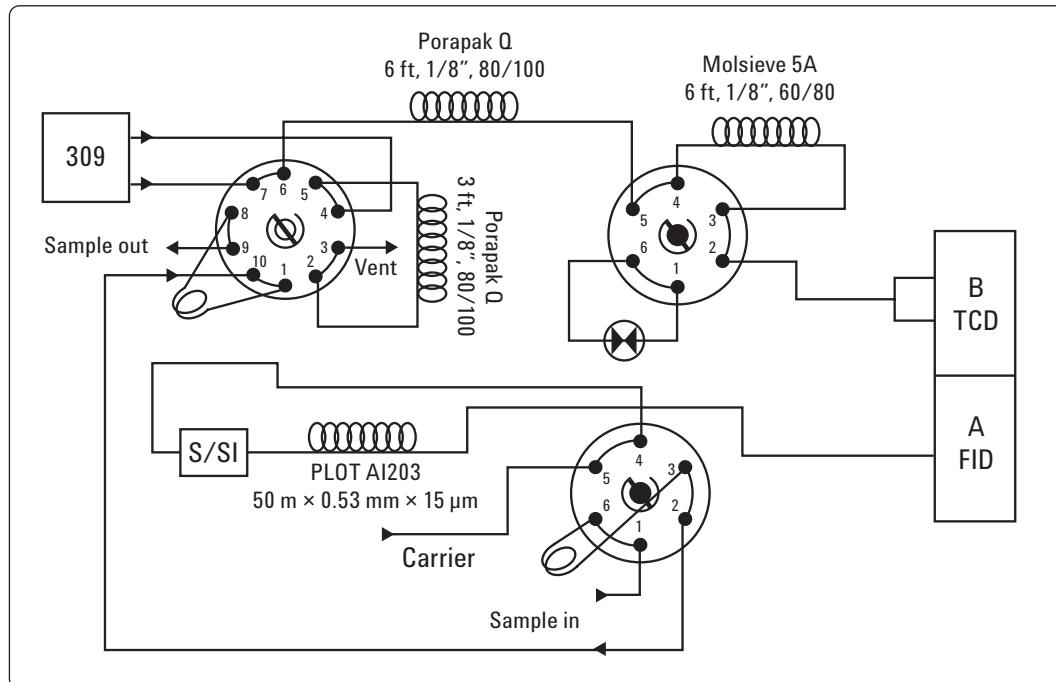


Figure 1. Valve diagram for dual-channel natural gas analysis.

Table 3. Concentrations of the Standard Gases

Components	H ₂	O ₂	N ₂	CO	CO ₂	CH ₄	C ₂ H ₆	C ₃ H ₈	iC ₄	nC ₄	iC ₅	nC ₅	nC ₆
Conc. (%)	6.09	3.00	9.97	1.99	3.48	71.92	2.00	0.99	0.11	0.10	0.12	0.12	0.11

Results

Chromatograms

Chromatograms for the FID and TCD channels of standard gas are shown in Figures 2 and 3. Hydrocarbons from C1 to C6 are separated by a PLOT Al₂O₃ column in approximately 15 minutes. For natural gas samples containing hydrocarbons higher than C6, the final temperatures of the oven program can be modified to 220 °C for the elution of hydrocarbons up to C11.

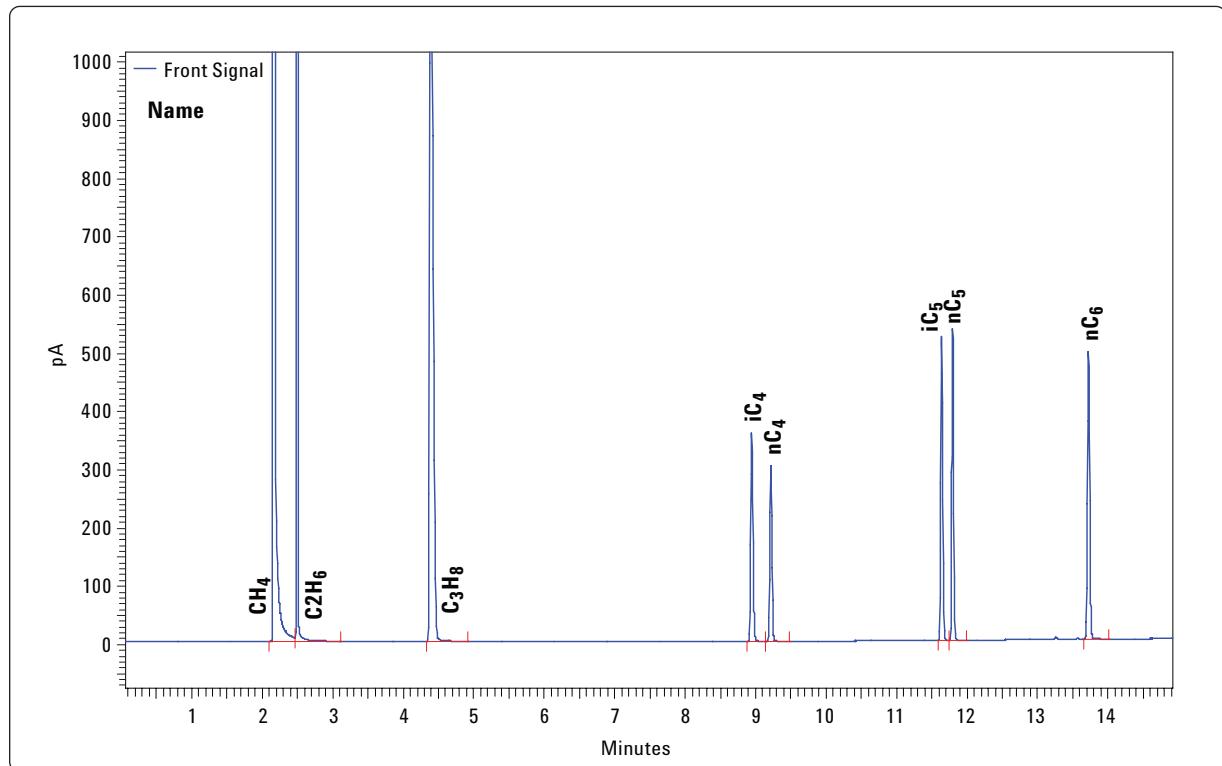


Figure 2. FID Channel chromatogram of CH₄, C₂H₆, C₃H₈, iC₄, nC₄, iC₅, nC₅ and nC₆

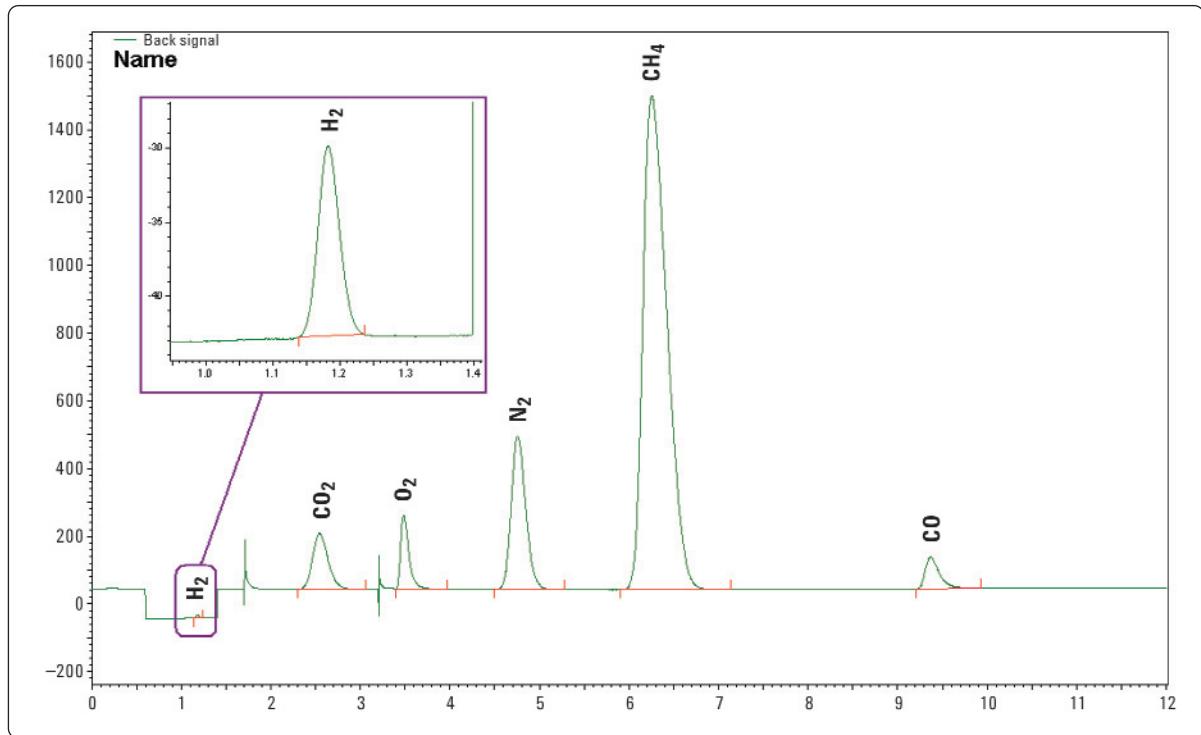


Figure 3. TCD Channel chromatogram of H_2 , O_2 , CO_2 , N_2 , CH_4 , CO .

Linearity

The mixed standard was dynamically diluted to five different lower-concentration levels for calibration. The linearity results of all the permanent gas components are listed in Table 4.

Table 4. Linearity Results of TCD Channel

%	H_2	CO_2	O_2	N_2	CH_4	CO
Level 1	0.305	0.174	0.150	0.500	3.596	0.100
Level 2	0.609	0.348	0.300	0.997	7.192	0.199
Level 3	1.523	0.870	0.750	2.493	17.98	0.498
Level 4	3.045	1.740	1.500	4.985	35.96	0.995
Level 5	6.090	3.480	3.000	9.970	71.92	1.990
R^2	0.999	0.999	0.998	1.000	0.999	0.999

Repeatability

The relative standard deviations (RSD) for all hydrocarbon components were lower than 0.8% by using split injection on the FID channel. This was due to the full electronic pneumatics control (EPC) from injector to detector on 7820A. Results of the TCD channel also show excellent repeatability (Table 5). Component concentrations were 0.305%, 0.174%, 0.15%, 0.5%, 3.596%, and 0.1%, respectively for H_2 , CO_2 , O_2 , N_2 , CH_4 , and CO .

Table 5. TCD Channel Repeatability

Runs	H_2	CO_2	O_2	N_2	CH_4	CO
1	10389	753601	137865	2180997	10904896	370250
2	10630	750304	142332	2191591	10947696	378184
3	10498	749748	140281	2156911	10926314	379868
4	10595	745289	139133	2168986	10822886	374996
5	10358	744909	140300	2172639	10826691	371749
RSD%	1.15	0.49	1.18	0.6	0.53	1.09

Low Level Permanent Gases

Another standard gas cylinder (Jiliang Standard Gas Inc., Shanghai) was tested by the 7820A 3-valve system to check low level response and repeatability. Figure 4 shows the chromatogram of the low level permanent gas mix and Figure 5 shows the overlapped chromatograms of five runs.

Chromatogram conditions and concentrations of each compound are listed as follows:

Carrier gas:	He
Sample loop:	1 mL
Oven:	45 °C (6 min) > 180 °C (2.25 min) at 20°C/min
TCD:	250 °C
1.	CO_2 200 ppm
2.	O_2 176 ppm
3.	N_2 Balance gas
4.	CH_4 810 ppm
*	Signal of valve switching

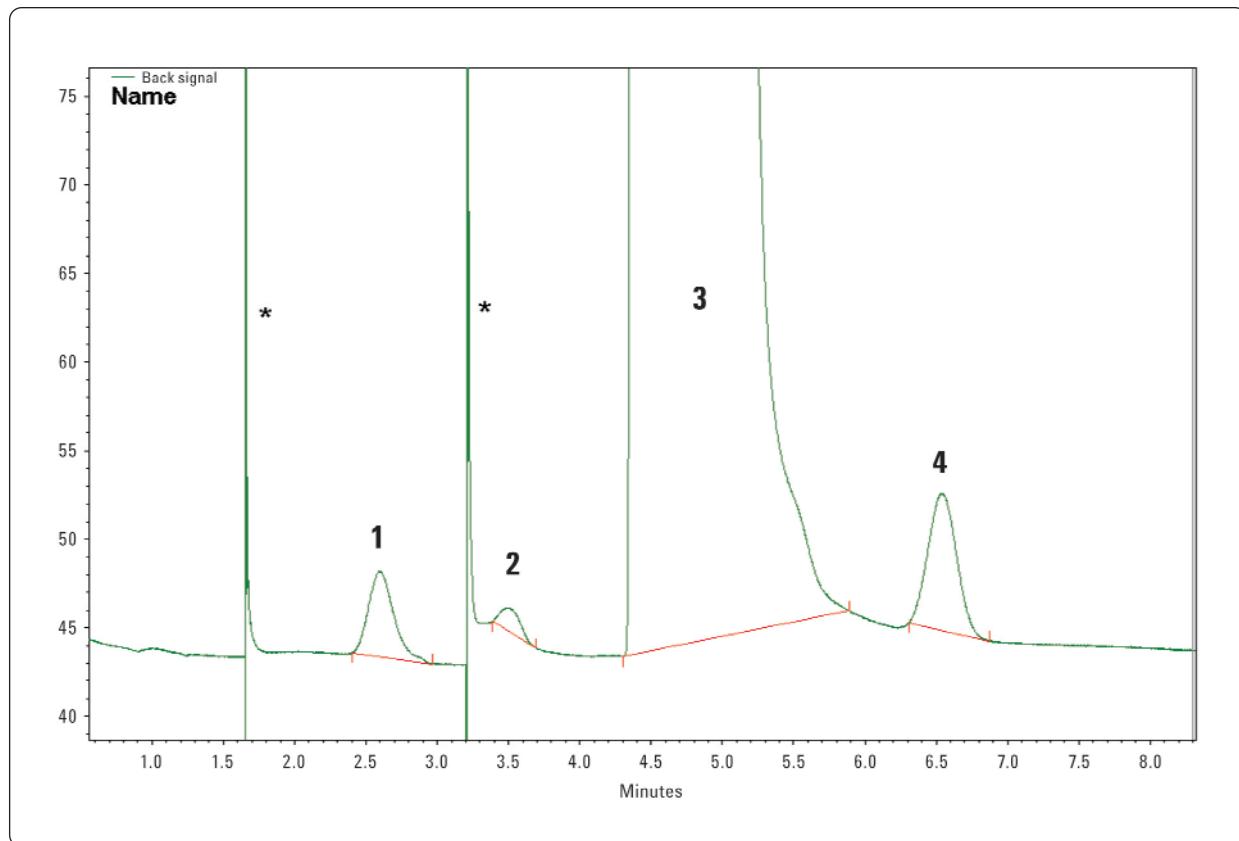


Figure 4. Chromatogram of low level permanent gas standard mix.

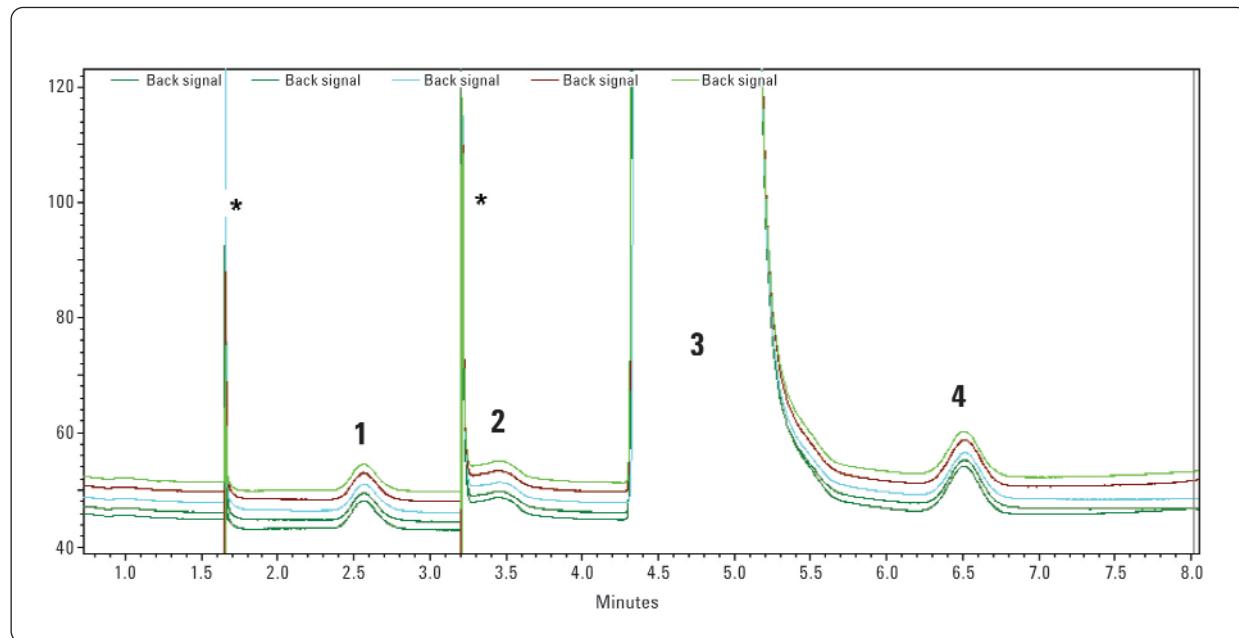


Figure 5. Overlapped chromatograms of five runs.

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